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Advances in Optical Thin Films VII

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Contents

DESIGN

- 11872 06 **Optimization of micro-cavities for huge enhancement patterns in free-space and modal space** [11872-3]
- 11872 08 **Non-polarizing narrow bandpass and other filters at angles** [11872-5]

CHARACTERIZATION

- 11872 0C **Giant saturable absorption in thin Sb₂Te₃ layers: development and characterization** [11872-9]

DEPOSITION PROCESSES I

- 11872 0E **Conformal antireflection coating on polycarbonate domes (Invited Paper)** [11872-11]
- 11872 0F **Ion beam sputtering of large scale dichroic mirror for fifth-harmonic separation** [11872-12]
- 11872 0G **Applying sacrificial substrate technology to miniaturized precision optical thin-film coatings** [11872-13]
- 11872 0I **Sputtered SiOxNy thin films: improving optical efficiency of liquid crystal diffuser elements in multi-focal near-to-eye display architecture** [11872-15]

DEPOSITION PROCESSES II

- 11872 0J **Properties of new transparent polymers for optical applications (Invited Paper)** [11872-16]
- 11872 0K **Xanthine: a promising organic material for the development of nanostructured anti-reflective layers** [11872-17]
- 11872 0L **Enhanced durable silver mirrors with ion beam assisted deposition** [11872-18]
- 11872 0M **Fabrication of phosphorescent oxide coatings using the aerosol deposition technique** [11872-19]
- 11872 0N **A study on sputtered ultrathin chromium films for optical applications** [11872-20]

OPTICAL MONITORING

11872 0Q **Optical monitoring of coating production: correlation of errors and errors self-compensation** [11872-23]

LIGHT SCATTERING STUDIES AT INSTITUT FRESNEL

11872 0S **Characterization of light backscattered from optical components using balanced low coherence interferometry** [11872-25]

HIGH-POWER LASER APPLICATIONS

11872 0X **Highly resistant all-silica polarizers for normal incidence applications (Invited Paper)** [11872-30]

11872 0Z **Photo-induced thermal radiation within multilayers optics** [11872-33]

11872 10 **Sculptured thin film based all-silica mirrors for high power lasers** [11872-34]